# ORIOF Angular Rate and Dual-Axis Linear Acceleration Combi-Sensor **CMS390** Technical Datasheet



## **Features**

- Small (10.4 x 6.7 x 2.7mm)
- Proven and robust silicon MEMS vibrating ring gyro and dual-axis accelerometer
- Excellent bias over temperature (1.75˚/s, 30mg)
- Flat and orthogonal mounting options (CMS300 and CMS390)
- User selectable dynamic ranges (150˚/s, 300˚/s, 2.5g and 10g)
- Digital (SPI®) output mode
- User selectable bandwidth (Rate; 45, 55, 90 or 110Hz Acc; 45, 62, 95 or 190Hz)
- Range and bandwidth independently selectable for each axis
- Low power consumption (8mA) from 3.3V supply
- High shock and vibration rejection
- Temperature range -40 +125˚C
- Hermetically sealed ceramic LCC surface mount package for temperature and humidity resistance
- Integral temperature sensor
- RoHS compliant

# **Applications**

- Measurement and control
- Navigation and personal navigation
- Inertial Measurement Units
- Inclinometers/tilt sensors
- Low cost AHRS and attitude measurement
- Levelling
- Robotics

# **1 General Description**

Orion™ is a new family of integrated MEMS inertial 'Combi-Sensors' from Silicon Sensing, combining high performance single-axis angular rate and dual-axis linear acceleration measurement in a small surface mounted package. It comprises two discrete MEMS sensing devices with a dedicated control ASIC in a single ceramic LCC package. Sensor data is output onto a SPI® digital interface. Dynamic range and bandwidth of all three channels can be independently selected by the user for optimal sensitivity. Two package configurations are available; part numbers CMS300 (Flat) and CMS390 (Orthogonal).

The datasheet relates to the CMS390 part. CMS390 provides the in-plane angular rate sensing (Z axis parallel to the PCBA), and two axes of linear acceleration where the X axis is parallel (in-plane) to the PCBA and the Y axis is perpendicular (out-ofplane) to the PCBA.

Angular rate is accurately measured using Silicon Sensing's proven 5th generation VSG5 Silicon MEMS ring gyroscope with multiple piezoelectric actuators and transducers. The 3mm ring is driven into resonance by a pair of primary drive actuators. Primary pick-off transducers provide closed loop control of ring amplitude and frequency. Pick-off transducers detect rate induced motion in the secondary axis, due to Coriolis force effects, the amplitude of which is proportional to angular velocity.

Precise linear acceleration sensing is achieved by a Silicon MEMS detector forming an orthogonal pair of sprung masses. Each mass provides the moving plate of a variable capacitance formed by an array of interlaced 'fingers'. This structure also provides critical damping to prevent resonant gain. Linear acceleration results in a change of capacitance which is measured by demodulation of the square wave excitation. The sensor has high linearity and shock resistance.

ASIC processing includes rate and acceleration bias, bias temperature sensitivity and scale factor sensitivity trim for all three sensors allowing sensor calibration over temperature in production.

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**Figure 1.1 CMS390 Functional Block Diagram**



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# **3 Specifi cation**

Unless stated otherwise, the following specification values assume  $Vdd = 3.15V$  to  $3.45V$  and an ambient temperature of +25°C. 'Over temperature' refers to the temperature range -40°C to +125°C.



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### **Specification Continued**







### **Specification Continued**





# **Specification Continued**





# **4 Absolute Minimum/Maximum Ratings**



#### **Notes:**

- 1. Turn on bias is specified at  $25 \pm 5^\circ$ C and at a power supply voltage of 3.3V. At other power supply voltages, a bias change of typically 40mg/V can be expected.
- 2. Exposure to the Absolute Maximum Ratings for extended periods may affect performance and reliability.

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## **5 Typical Performance Characteristics**

Graphs showing typical performance characteristics for Orion™ are shown below: **Note:** Typical data is with the device powered from a 3.3V supply.

## **Rate Channel**



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# **Typical Performance Characteristics Continued**

# **Rate Channel**



# **Rate and Acceleration CBIT**







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# **Typical Performance Characteristics Continued Acceleration Channels**



**Figure 5.13 Acceleration Bias at 25°C (±10g)**



**Figure 5.14 Acceleration Bias at 25°C (±2.5g)**



**Figure 5.15 Accelerometer Y Bias vs Temperature (±10g)**







**Figure 5.16 Accelerometer Y Bias vs Temperature (±2.5g)**









# **Typical Performance Characteristics Continued Acceleration Channels**



#### **Figure 5.19 Accelerometer Y SF Error vs Temperature (±10g)**



**Figure 5.21 Accelerometer X SF Error vs Temperature (±10g)**



#### **Figure 5.20 Accelerometer Y SF Error vs Temperature (±2.5g)**



**Figure 5.22 Accelerometer X SF Error vs Temperature (±2.5g)**

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**6 Glossary of Terms**



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# **7 Interface**

Physical and electrical inter-connect and SPI® message information.

#### **7.1 Physical and Electrical Interface, Pad Layout and Pinouts**





**Figure 7.3 Peripheral Circuit**

C.G.18572

### **Figure 7.1 Pinout (Top View)**



C.G. 18571

All dimensions in millimetres.

### **Figure 7.2 Recommended Pad Layout**

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### **Table 7.1 Input/Output Pin Definitions**



#### **Table 7.2 Electrical Characteristics**

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This section defines the SPI® interface timing and the message types and formats to and from the Orion™ CMS390 sensor. It also defines the memory maps of the internal functional memory.

The SPI® interface, when selected, will be a 4-wire interface with the following signals:



Signal electrical characteristics are defined in Table 7.3.



### **Table 7.3 SPI® Electrical Characteristics**

The interface will transfer 4 bytes (32 bits) in each message. The message rate will be 1kHz (nom), (1Hz-min, 10kHz-max) with a SPI® clock frequency of 1MHz (nom), (100kHz-min, 7MHz-max).

The sensor will be a slave on the interface. All accesses shall use SPI® Mode 0.

Figure 7.4 below specifies the interface timing for correct operation.



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# **7.2.1 Messages to Sensor (MOSI)**

Table 7.4 outlines the command message types available from the host to the Orion<sup>TM</sup> sensor:



#### **Table 7.4 Command Message Types**

Table 7.5 details the command bit format for messages to the Orion™ sensor:



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#### **Table 7.5 Command Message Format**

- **NOTE 1:** CBIT\_en: 0 = inactive, 1= active. See section 7.2.6 for CBIT behaviour.
- **NOTE 2:** In all messages to and from the sensor a 4-bit CRC (data bits D3:0) shall be added. The CRC polynomial used shall be  $x^4+1$ . A seed value of "1010" shall be used with a calculation order MSB to LSB. The CRC shall be checked for all I/P messages. If the CRC fails then the message shall be ignored and a SPI® error message output in the next message.

# **7.2.2 Messages from Sensor (MISO)**

Table 7.6 outlines the status message types available from the Orion™ sensor to the host:



#### **Table 7.6 Status Message Types**

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#### **Table 7.7 Status Message Format**

- **NOTE 1:** CBIT = 1 if CBIT is Active, 0 if CBIT is inactive. See section 7.2.6 for CBIT behaviour.
- **NOTE 2:** If D15:14 = "01" then a fault condition has been detected.
- **NOTE 3:** Acc Bit will be set to fail (1) if a fault with the accelerometer channels is detected. If it indicates a pass (0) then the acc channels are still operational even if bits D15:14 indicate a fault.
- **NOTE 4:** KACT = Keep alive count; a 2 bit count that increments every data monitor message and rolls over at "11".
- **NOTE 5:** On POR or from Reset the first message type from the sensor shall be the configuration status, for any command message.
- **NOTE 6:** On receipt of one of the following command message types in SPI® exchange (N) the response sent in the next SPI® exchange (N+1) will be that output in SPI exchange (N-1). NVM Write Data

 NVM Write NVM Erase

**NOTE 7:** If an invalid command message or a SPI® error message is sent by the ASIC then this message will be held until a valid status message request has been requested i.e. a message listed in section 7.2.2.

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- **NOTE 8:** In all messages to and from the ASIC a 4-bit CRC (data bits D3:0) shall be added. The CRC polynomial used shall be x<sup>4</sup>+1. A seed value of "1010" shall be used with a calculation order MSB to LSB. The CRC shall be checked for all I/P messages. If the CRC fails then the message shall be ignored and a SPI® error message output in the next message.
- **NOTE 9:** The rate data shall be a 16 bit 2's complement number, where a rate O/P of 0000h = 0°/s. Scale factor 204.8 lsb/(°/s) – Low Range, 102.4 lsb/(°/s) – High Range.
- **NOTE 10:** The acceleration data shall be a 16 bit 2's complement number, where acc output of 0000h = 0g. Scale factor 12800 lsb/g (low range), 3200 lsb/g (high range).
- **NOTE 11:** The temperature data shall be a 16 bit number, as follows -40°C = 06A4h (170010), 0°C = 0852h (213010), +25°C = 0960h (240010). Scale factor 0.091°C/lsb (or 10.99 lsb/°C).

# **7.2.3 BIT Flag Format**

The BIT status message data word is enclosed as defined in table 7.8.



#### **Table 7.8 BIT Status Format**

## **7.2.4 REV and INREV Format**

The REV and INV REV messages can be decoded as follows:

The Device ID and revision numbers will be stored in the NVM.

REV contains devices ID and revision. The message is encoded as defined in table 7-9.



#### **Table 7.9 REV Message Format**

INV REV contains devices ID and revision. The message is encoded as defined in table 7-10.



### **Table 7.10 INV REV Message Format**

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# **7.2.5 Device Configuration**

The default device configuration is stored in location 00 of the NVM (see section 8.2). To change the default device configuration see section 8.3. This data is loaded on power-up or reset. This data can be over-ridden by a SPI® Device Configuration Set message with the following data format. A SPI® configuration selection is latched and cannot be overwritten by any further Device Configuration messages. A power or reset cycle will be required to clear the SPI® selection and reload the default NVM selection.

A device configuration status request will output the configuration currently in use within the device. The status format is defined in table 7-11.



**Note 1:** See figure 1.2 for definition of positive sense direction.

#### **Table 7.11 Configuration Status Message Format**

# **7.2.6 CBIT**

A CBIT function can be used to check the operation of the internal control loops.

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When enabled, via a SPI® message CBIT will add a fixed offset to the Rate and both Acceleration outputs, BIT\_Out will be set to the fault condition and the sensor message will show a fault. The offset applied depends on the range selected. See page 5 and 6 for details.

# **8 NVM Memory**

The NVM will be an EEPROM block with 32 locations of 16 bit data plus 6 bit ECC parity. The ECC parity bits will be able to correct single bit errors. The EEPROM block will generate two error bits; one if a single bit error is detected the other if multiple error bits are detected.

The memory will be split into two areas of 13 and 19 locations of 16 bit words.

The first area (address 00 to 0C) allows unlimited read, write or erase access by the User. The first location (address 00) is used to configure the device (e.g. Bandwidth, Range selection – see section 8.2). The remaining locations have no limitations on data content.

The second area (address 0D to 1F) is used to store calibration, setup and serial number data. The User will only be allowed read access of the serial number data (locations 0D to 10). Access to all other locations in this area are not allowed.

Section 8.3 details the sequence of messages required for each operation.

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# **8.1 NVM Memory Map**

Table 8.1 details the content and accesses allowed for each location in the NVM.



**Note:** Access codes: R, W, E - Unlimited Read, Write or Erase.

#### **Table 8.1 NVM Memory Map**

# **8.2 Confi guration Word Format**

The device configuration data stored in location 00(hex) of the NVM shall have the format defined in table 8.2. Factory default settings 0FF8 (h).



**Note 1:** See figure 1.2 for definition of positive sense direction.

#### **Table 8.2 Configuration Format in NVM**

### **8.3 NVM Operations**

This section defines the steps required for NVM access operations.

#### **Read from User NVM location:**

Reads from the user area of the NVM or the serial number locations.

 1. NVM Read SPI® message requesting data from NVM address specified in message.

# **Write to User NVM location:**

The for correct storage of required data the location must be erased before writing new data.



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- 1. NVM Write Data message containing the 16-bit data to be written.
- 2. NVM Write command containing the 5 bit NVM address to be written to.

#### **Erase of User NVM location:**

 1. NVM Erase message containing the 5 bit NVM address to be erased.

# **9 Design Tools and Resources Available**



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# **Design Tools and Resources Available Continued**



## **10 Cleaning**

Due to the natural resonant frequency and amplification factor  $({}^{\prime}Q^{\prime})$  of the sensor, ultrasonic cleaning should NOT be used to clean the Orion™ Combi Sensor.

# **11 Soldering Information**



#### **Figure 11.1 Recommended Reflow Solder Profile**

# **12 Part Markings**



#### **Figure 12.1 Part Marking**



### **Table 12.1 Production Number Code**



### **Table 12.2 Assembly Lot Code**

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# **13 Packaging Information**



#### **Table 13.1 Packaging Information**



### **Table 13.2 Packaging Specification**

#### **Reel Information**



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### **Emboss Tape Carrier Information**



#### **Tape Information**



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**Label for Reel Information Inner Bag Packing Information Inner Box Packing Information Outer Box Packing Information** CMS390 No. S3011002001 Part Number Number C.G. 18596 C.G. 18392 Desiccant Inner Bag  $R_{\ell}$ C.G. 18389 Inner Bag **Inner Box** C.G. 1839  $\mathbb{C}^2$ Maximum of two Reels per Outer Box. If 1 Reel is contained in Outer Box, label is pasted in position 1. If 2 Reels are contained in Outer Box, labels are pasted in positions 1 and 2. Each label shows packaged reel information. Box Craft Tape Pad **Tray** Inner Box Pad **Tray** Inner Box Pad

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# **14 Internal Construction and Theory of Operation**

#### **Construction**

Orion™ is available in two basic package configurations: Part Number CMS300 (flat): Relative to the plane of the host PCBA, this part measures angular velocity about a single perpendicular axis (Z) and linear acceleration about two parallel axes (X,Y).

Part Number CMS390 (orthogonal): Relative to the plane of the host PCBA, this part measures angular velocity about a single parallel axis (Z) and linear acceleration about one parallel axis (X) and one perpendicular axis (Y).

Orion™ (CMS300 and CMS390) is supplied as a PCBA surface mountable LCC ceramic packaged device. It comprises six main components; Silicon MEMS Single-Axis Angular Rate Sensor, Silicon On Glass (SOG) Dual-Axis MEMS Accelerometer, Silicon Pedestal, ASIC and the Package Base and Lid. The MEMS Sensors, ASIC and Pedestal are housed in a hermetically sealed package cavity with a nitrogen back-filled partial vacuum, this has particular advantages over sensors supplied in plastic packages which have Moisture Sensitivity Level limitations.

A exploded drawing of CMS300 showing the main components is given in Figure 14.1 below. The principles of construction for CMS390 are the same as CMS300.



**Figure 14.1 CMS300 Main Components**



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**Figure 13.2 CMS300 (Lid Removed)**

#### **Silicon MEMS Ring Sensor (Gyro)**

The 3mm diameter by 65μm thick silicon MEMS ring is fabricated by Silicon Sensing using a DRIE (Deep Reactive Ion Etch) bulk silicon process. The annular ring is supported in free-space by eight pairs of 'dog-leg' shaped symmetrical spokes which radiate from a central 1mm diameter solid hub.

The bulk silicon etch process and unique patented ring design enable close tolerance geometrical properties for precise balance and thermal stability and, unlike other MEMS gyros, there are no small gaps to create problems of interference and stiction. These features contribute significantly to Orion™'s bias and scale factor stability over temperature, and vibration and shock immunity. Another advantage of the design is its inherent immunity to acceleration induced rate error, or 'g-sensitivity'.

Piezoelectric (strain) film actuators/transducers are attached to the upper surface of the silicon ring perimeter and are electrically connected to bond pads on the ring hub via tracks on the spokes. These actuate or 'drive' the ring into its  $Cos2 $\theta$  mode$ of vibration at a frequency of 22kHz or detect radial motion of the ring perimeter either caused by the primary drive actuator or by the coriolis force effect when the gyro is rotating about its sensing axis. There is a single pair of primary drive actuators and a single pair of primary pick-off transducers, and two pairs of secondary pick-off transducers.

The combination of transducer technology and eight secondary pick-off transducers improves Orion<sup>™'s</sup> signal-to-noise ratio, the benefit of which is a very low-noise device with excellent bias over temperature performance.

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#### **Silicon MEMS Dual-Axis Accelerometer**

The Orion™ dual-axis open loop accelerometer is a one-piece resonating silicon MEMS structure anodically bonded to top and bottom glass substrates to form a hermetically sealed Silicon on Glass (SOG) wafer sub-assembly. The same DRIE bulk silicon process as used to create the gyro in Orion™ is used to create two orthogonal finger-like spring/seismic proof mass structures, each measuring 1.8mm square, and with a resonant frequency of 2.9kHz. Figure 14.4 shows a schematic cross section through the SOG wafer.

Capacitive drive and pick-off signals are transmitted by wire bond interconnections, in through-glass vias, between the metallised transducer plates on the MEMS proof mass and the Orion™ ASIC.

Multiple inter-digitated fingers create increased capacitance thus enabling a high signal-to-noise ratio. The fingers are tapered to increase the resonant frequency and also have a high aspect ratio to provide highly stable performance. The differential gaps between the static electrode fingers and those of the proof mass provide an air squeeze film with nearcritical damping.

Control of the accelerometer is handled by the Orion<sup>™</sup> ASIC.



#### **Figure 14.4 Schematic Section of the Silicon On Glass Accelerometer MEMS Wafer Sub-Assembly**

#### **Pedestal**

The hub of the MEMS ring is supported above the ASIC on a 1mm diameter cylindrical silicon pedestal, which is bonded to the ring and ASIC using an epoxy resin.

### **ASIC**

The ASIC is a 5.52mm x 3.33mm device fabricated using 0.35μm CMOS process. ASIC and MEMS are physically separate and are connected electrically by using gold bond wires and thus the ASIC has no MEMS-to-ASIC internal tracking, meaning there is reduced noise pick-up and excellent EMC performance. Gold bond wires also connect the ASIC to the internal bond pads on the Package Base.

#### **Package Base and Lid**

The LCC ceramic Package Base is a multi-layer aluminium oxide construction with internal bond wire pads connected through the Package Base via integral multi-level tungsten interconnects to a series of external solder pads. Similar integral interconnects in the ceramic layers connect the Lid to Vss, thus the sensitive elements are inside a Faraday shield for excellent EMC. Internal and external pads are electroplated gold on electroplated nickel.

The Package Base incorporates a seal ring on the upper layer onto which a Kovar® metal Lid is seam welded using a rolling resistance electrode, thus creating a totally hermetic seal. Unlike other MEMS gyro packages available on the market, Orion™ has a specially developed seam weld process which eliminates the potential for internal weld spatter. Inferior designs can cause dislodged weld spatter which affects gyro reliability due to interference with the vibratory MEMS element, especially where the MEMS structure has small gaps, unlike Orion<sup>™</sup> with its large gaps as described above.

#### **Theory of Operation (Gyro)**

Orion™ rate sensor is a solid-state device and thus has no moving parts other than the deflection of the ring itself. It detects the magnitude and direction of angular velocity by using the 'coriolis force' effect. As the gyro is rotated coriolis forces acting on the silicon ring cause radial movement at the ring perimeter.

There are eight actuators/transducers distributed evenly around the perimeter of the silicon MEMS ring. Located about its primary axes (0° and 90°) are a single pair of 'primary drive' actuators and a single pair of 'primary pick-off' transducers. Located about its secondary axes (45° and 135°) are two pairs of 'secondary pick-off' transducers.



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The 'primary drive' actuators and 'primary pick-off' transducers act together in a closed-loop system to excite and control the ring primary operating vibration amplitude and frequency (22kHz). Secondary 'pick-off' transducers detect radial movement at the secondary axes, the magnitude of which is proportional to the angular speed of rotation and from which the gyro derives angular rate. The transducers produce a double sideband, suppressed carrier signal, which is demodulated back to a baseband. This gives the user complete flexibility over in system performance, and makes the transduction completely independent of DC or low frequency parametric conditions of the electronics.

#### Referring to Figures 14.3(a) to 14.3(d)

Figure 14.3(a) shows the structure of the silicon MEMS ring. Figure 14.3(b) shows the ring diagrammatically, the spokes, actuators and transducers removed for clarity, indicating the Primary Drive actuators (single pair), Primary Pick-Off transducers (single pair) and Secondary Pick-Off transducers (two pairs). In Figure 14.3(b) the annular ring is circular and is representative of the gyro when unpowered.

When powered-up the ring is excited along its primary axes using the Primary Drive actuators and Primary Pick-Off transducers acting in a closed-loop control system within the ASIC. The circular ring is deformed into a 'Cos2θ' mode which is elliptical in form and has a natural frequency of 22kHz. This is depicted in Figure 14.3(c). In Figure 14.3(c) the gyro is powered-up but still not rotating. At the four Secondary Pick-Off nodes located at 45° to the primary axes on the ring perimeter there is effectively no radial motion.

If the gyro is now subjected to applied angular rate. as indicated in Figure 14.3(d), then this causes the ring to be subjected to coriolis forces acting at a tangent to the ring perimeter on the primary axes. These forces in turn deform the ring causing radial motion at the Secondary Pick-Off transducers. It is the motion detected at the Secondary Pick-off transducers which is proportional to the applied angular rate. The DSBSC signal is demodulated with respect to the primary motion, which results in a low frequency component which is proportional to angular rate. All of the gyro control circuitry is hosted in the ASIC. A block diagram of the ASIC functions is given in Figure 1.1 in Section 1.



C.G. 18400

**Figure 14.3(c)**

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**Figure 14.3(d)**

The accelerometer contains a seismic 'proof mass' with multiple fingers suspended via a 'spring', all of which is formed in the silicon MEMS structure. The proof mass is anodically bonded to the top and bottom glass substrates and thereby fixed to the

When the Orion<sup>™</sup> sensor is subjected to a linear acceleration along its sensitive axis the proof mass tends to resist motion due to its own inertia, therefore the mass and it's fingers becomes displaced with respect to the interdigitated fixed electrode fingers. Air between the fingers provides a damping effect. This displacement induces a differential capacitance between the moving and fixed silicon fingers which is proportional to the

**Theory of Operation (Accelerometer)** 



#### **Figure 14.5(a) Schematic of Accelerometer Structure**



#### **Figure 14.5(b) Schematic of Accelerometer Control Loop**

# **15 Patent Applications**

The following patent applications have been filed for the Orion™ Combi Sensors:



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#### finger groups. The demodulated waveforms provide a signal output proportional to linear acceleration.

applied acceleration.

Orion<sup>™</sup> Package Base.

Figures 14.5(a) and 14.5(b) provide schematics of the accelerometer structure and control loop respectively.

Capacitor plate groups are electrically connected in pairs at the top and bottom of the proof mass. In-phase and anti-phase waveforms are applied by the Orion<sup>™</sup> ASIC separately to the 'left' and 'right'

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